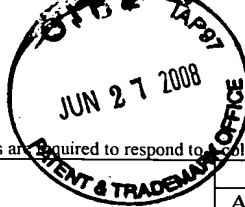


PTO/SB/08a (08-03)
Approved for use through 07/31/2006. OMB 0651-0031
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE
tion of information unless it contains a valid OMB control number.



Substitute for form 1449A/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT***(use as many sheets as necessary)*

Complete if Known

Application Number	10/551,714
Filing Date	July 20, 2006
First Named Inventor	Yair EIN-ELI et al
Group Art Unit	1793
Examiner Name	PARVINI, PEGAH
Attorney Docket Number	30579

Sheet	2	Of	2
OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	15	Chan et al. "Oxide Film Formation and Oxygen Adsorption on Copper in Aqueous Media as Probed by Surface-Enhanced Raman Spectroscopy", Journal of Physical Chemistry, B, 103: 357-365, 1999.	
	16	Feng et al. "Corrosion Mechanisms and Products of Copper in Aqueous Solutions at Various pH Values", Corrosion, 53(5): 398-407, May 1997.	
	17	Hamilton et al. "In Situ Raman Spectroscopy of Anodic Films Formed on Copper and Silver in Sodium Hydroxide Solution", Journal of the Electrochemical Society, 139: 739-745, 1986.	
	18	Kunze et al. "In Situ Scanning Tunneling Microscopy Study of the Anodic Oxidation of Cu(111) in 0.1 M NaOH", Journal of Physical Chemistry B, 105: 4263-4269, 2001.	
	19	Maurice et al. "In Situ Scanning Tunneling Microscope Study of the Passivation of Cu(111)", Journal of the Electrochemical Society, 146(2): 524-530, 1999.	
	20	Maurice et al. "In Situ STM Study of the Initial Stages of Oxidation of Cu(111) in Aqueous Solution", Surface Science, 458: 185-194, 2000.	
	21	Mayer et al. "An In Situ Raman Spectroscopy Study of the Anodic Oxidation of Copper in Alkaline Media", Journal of Electrochemical Society, 139(2): 426-434, February 1992.	
	22	Melendres et al. "In-Situ Synchrotron Far Infrared Spectroscopy of Surface Films on A Copper Electrode in Aqueous Solutions", Journal of Electroanalytical Chemistry, 449: 215-218, 1998.	
	23	Steigerwald et al. "Electrochemical Potential Measurements During the Chemical-Mechanical Polishing of Copper Thin Films", Journal of the Electrochemical Society, 142(7): 2379-2385, July 1995.	
	24	Strehblow et al. "The Investigation of the Passive Behaviour of Copper in Weakly Acid and Alkaline Solutions and the Examination of the Passive Film by ESCA and ISS", Electrochimica Acta, 25: 839-850, 1980.	

Examiner Signature	Date Considered
--------------------	-----------------

* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional).

² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3).

³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3).

⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.

⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible.

⁶ Applicant is to place a check mark here if English language translation is attached.

This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.